

# Ex-situ Group V Doping of CdTe using Solution-based Processes

---

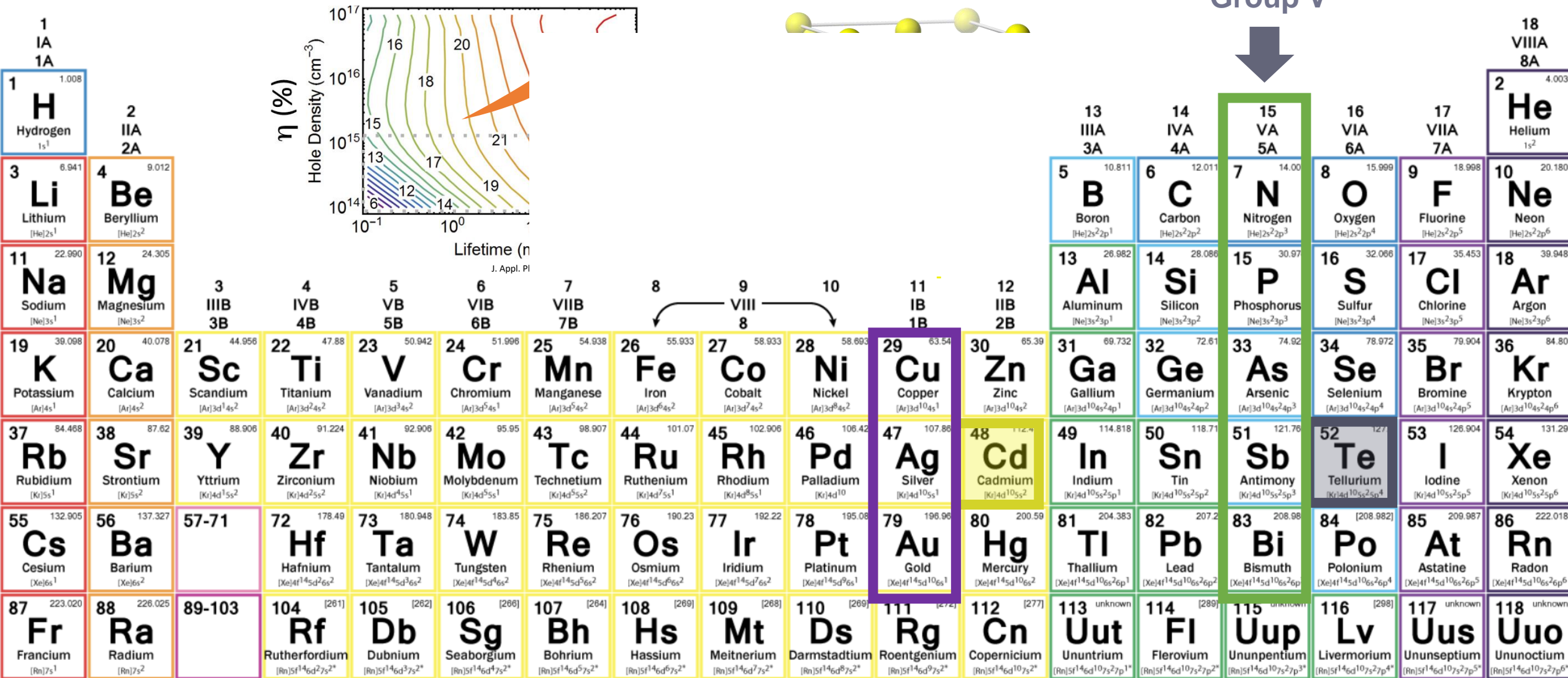
Xiaomeng Duan<sup>1</sup>, Sabin Neupane<sup>2</sup>, Dengbing Li<sup>2</sup>, Harigovind Gokul Menon<sup>1</sup>, Dingyuan Lu<sup>3</sup>, Gang Xiong<sup>3</sup>, Yanfa Yan<sup>2</sup>, **Feng Yan**<sup>1</sup>

1. Department of Metallurgical and Materials Engineering, The University of Alabama, Tuscaloosa, AL, USA 35487
2. Department of Physics and Astronomy, The University of Toledo, Toledo, OH, USA, 43606
3. California Technology Center, First Solar Inc., Santa Clara, CA, USA, 94105



# Group V Doping of CdTe

Group V



Configurations denoted with a \* are unknown and the listed values are predicted.

- Group V doping into the Te site to play as the acceptor

# Group V Doping Approaches in CdTe

## In situ vs Ex-situ

### Pros:

- Higher dopant concentration  $\sim 1 \times 10^{18}$
- Better control of Group V ions distribution

### Cons:

- Low activation ratio  $\sim 1\%$
- Possible dopant segregation

### Pros:

- Higher activation ratio  $\sim 5\%$
- Less dopant segregation

### Cons:

- Lower dopant concentration  $\sim 1 \times 10^{16}$
- Fixed distribution



### Exceeding 20% efficiency with in situ group V doping in polycrystalline CdTe solar cells 2019

W. K. Metzger<sup>1\*</sup>, S. Grover<sup>2</sup>, D. Lu<sup>2</sup>, E. Colegrove<sup>1</sup>, J. Moseley<sup>1</sup>, C. L. Perkins<sup>1</sup>, X. Li<sup>2</sup>, R. Mallick<sup>2</sup>, W. Zhang<sup>2</sup>, R. Malik<sup>2</sup>, J. Kephart<sup>2</sup>, C.-S. Jiang<sup>1</sup>, D. Kuciauskas<sup>1</sup>, D. S. Albin<sup>1</sup>, M. M. Al-Jassim<sup>1</sup>, G. Xiong<sup>2</sup> and M. Gloeckler<sup>3</sup>

2022 ~ 22%



### Low-temperature and effective ex situ group V doping for efficient polycrystalline CdSeTe solar cells 2021 18%

Deng-Bing Li<sup>1</sup>, Canglang Yao<sup>1</sup>, S. N. Vijayaraghavan<sup>2</sup>, Rasha A. Awni<sup>1</sup>, Kamala K. Subedi<sup>1</sup>, Randy J. Ellingson<sup>1</sup>, Lin Li<sup>2</sup>, Yanfa Yan<sup>1</sup> and Feng Yan<sup>2</sup>

2022 ~ 19%

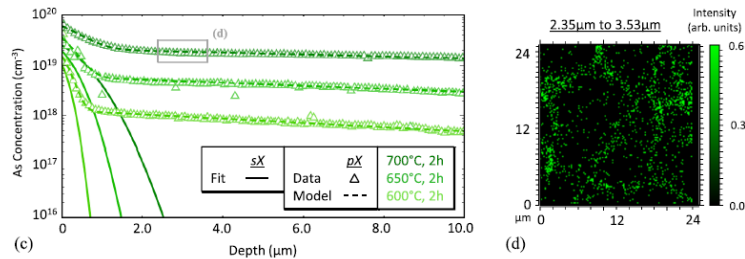
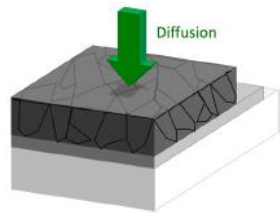


3

# Ex-situ Doping Approaches and Challenges in Polycrystalline CdTe

## • Dry diffusion doping

- Over-pressure of Cd group V covalent compounds.,
  - e.g.,  $\text{Cd}_3\text{As}_2$ ,  $\text{Cd}_3\text{P}_2$



*High diffusion temperature (550~700 °C) may not be suitable for the CdTe module manufacturing*

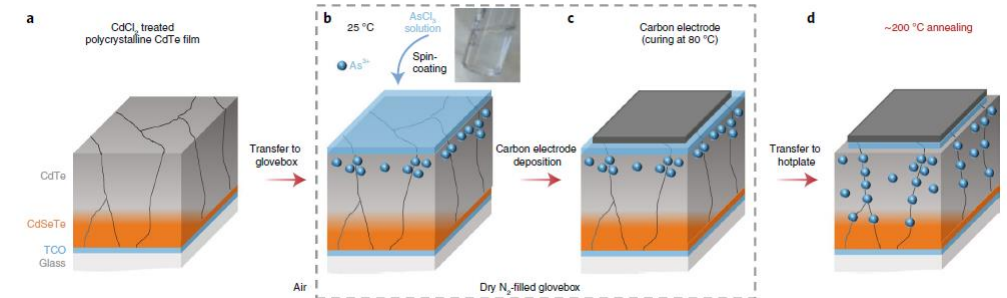
J. Phys. D: Appl. Phys. **51** (2018) 075102

- Group V chalcogenides layer,
  - e.g.,  $\text{Sb}_2\text{Te}_3$ ,  $\text{Bi}_2\text{Te}_3$  as back contact,  
*Low efficiency without Cu doping*

AIP Advances 1, 042152 (2011)  
Solar Energy Materials & Solar Cells 121 (2014) 92–98

## • Wet diffusion doping

- Group V halides ionic compounds
  - e.g.,  $\text{PCl}_3$ ,  $\text{AsCl}_3$ ,  $\text{SbCl}_3$ ,



Nature Energy, 6, 715–722 (2021)

*Low diffusion temperature, but compounds sensitivity to ambient moisture and toxicity.*

*Need air stable and less-toxicity ex-situ low temperature diffusion process*

# Challenges to Conduct the ex-situ Group V Doping in CdTe

- Understanding ex-situ Diffusion Doping mechanism
- Higher diffusion barrier of Group V in the CdTe Grain Interiors(GIs)/Grain Boundaries (GBs)
- Complicated surface chemistry of the diffusion doped CdTe surface
- Suitable back contact for the diffusion doped CdTe.
- Alternative group V dopants for ex-situ diffusion
- Desired activation process for the ex-situ diffusion doped CdTe
- Others, e.g., impurities (unintentional dopants)

# Challenges to Conduct the ex-situ Group V Doping in CdTe

- Understanding ex-situ Diffusion Doping mechanism
- Higher diffusion barrier of Group V in the CdTe Grain Interiors(GIs)/Grain Boundaries (GBs)
- Complicated surface chemistry of the diffusion doped CdTe surface
- Suitable back contact for the diffusion doped CdTe.
- Alternative group V dopants for ex-situ diffusion
- Desired activation process for the ex-situ diffusion doped CdTe
- Others, e.g., impurities (unintentional dopants)

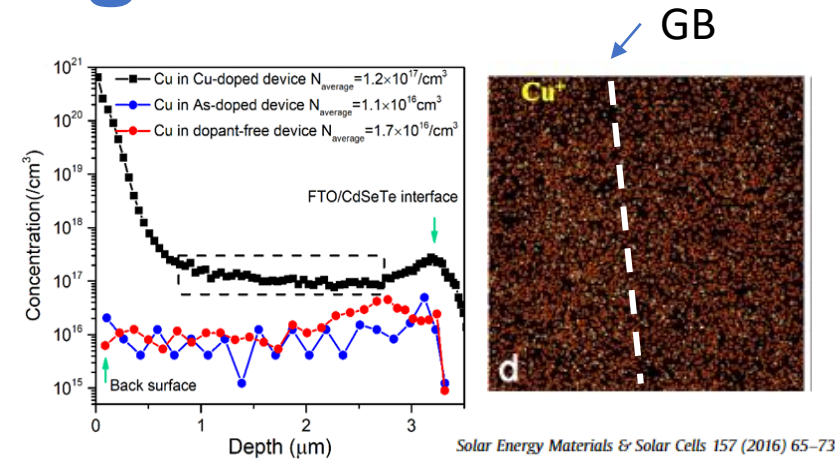
# Solution-processed Doping in CdTe

## Cu doping using the solution means

- CuCl CdCl<sub>2</sub> treated CdTe
  - CuCl<sub>2</sub> → P-type doping at Cd vacancies
  - CuSCN
  - CuNO<sub>3</sub>
  - others
- Surface reaction: Cu<sup>+2+</sup> + Te = Cu<sub>2</sub>Te
  - Defect chemistry: V<sub>Cd</sub><sup>''</sup> + Cu<sup>+</sup> = Cu<sub>Cd</sub><sup>'</sup> → hole
  - Cu ions faster diffusion in CdTe
  - Cu uniform distribution in the GBs/GIs
  - Cu activation ratio ~ <1%

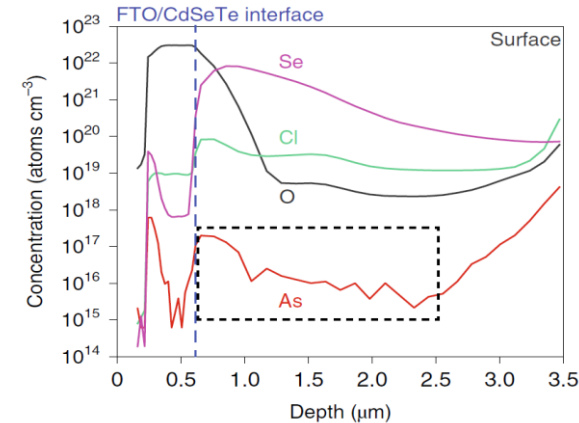
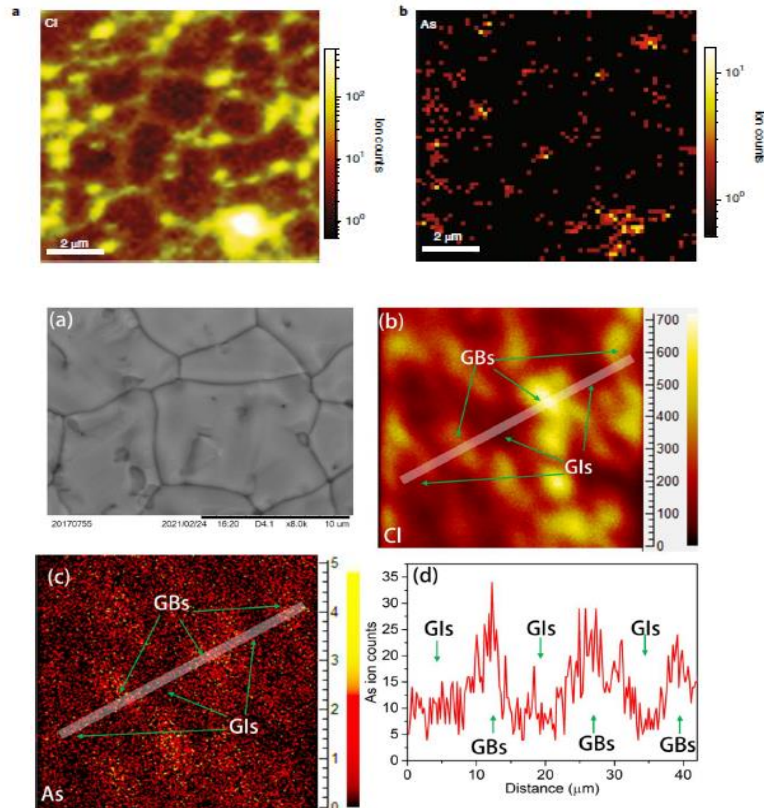
## Group V solutions doping in CdTe

- Group V halides in solutions
  - PCl<sub>3</sub>, AsCl<sub>3</sub>, SbCl<sub>3</sub>, BiCl<sub>3</sub>, etc
  - Diffusion barrier: Cations < anions
  - Cations diffusion barrier similar with Cu

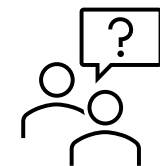
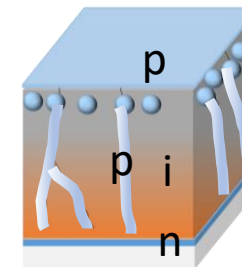


Diffusion constant and activation energy of intrinsic and extrinsic defects in CdTe			
Dopants	defect states	Diffusion constant, D <sub>0</sub> , cm <sup>2</sup> s <sup>-1</sup>	Diffusion activation energy, E <sub>D</sub> , eV
intrinsic	V <sub>Cd</sub> <sup>2-</sup>		1.08 (cal)
	Cd <sup>0</sup>		0.35
	Cd <sub>i</sub> <sup>+</sup>		0.39
Cu	total	7.73 × 10 <sup>-7</sup> (exp)	0.33 (exp)
Cu	total	7.4 × 10 <sup>-6</sup> (bulk, exp), 2.3 (GB, exp)	0.84 (bulk, exp), 1.1 (GB, exp)
	Cu <sub>Cd</sub> <sup>-</sup>		1.23 (cal) 0.72 (cal)
P	total	4.86 × 10 <sup>-3</sup> (bulk), 6.61 × 10 <sup>2</sup> (GB)	2.10 (bulk, exp), 1.97 (GB, exp)
	P <sub>i</sub> <sup>3+</sup>		0.43 (Te rich, cal)
	P <sub>i</sub> <sup>3-</sup>		1.08 (Cd rich, cal)
As	total	9.4 × 10 <sup>-2</sup> (bulk), 1.05 × 10 <sup>3</sup> (GB)	2.18 (bulk, exp), 2.34 (GB, exp)
	As <sub>i</sub> <sup>3+</sup>		0.49 eV (Te rich, cal)
	As <sub>i</sub> <sup>3-</sup>		0.84 eV (Cd rich, cal)
Sb	total	1.15 × 10 <sup>1</sup> (bulk), 4.39 × 10 <sup>1</sup> (GB)	2.52 (bulk, exp), 1.71 (GB, exp)
	Sb <sub>Cd</sub> <sup>+</sup>		0.55 eV (cal)
	Sb <sub>i</sub> <sup>3+</sup>		1.03 (cal)
	Sb <sub>i</sub> <sup>3+</sup>		0.20 (Te rich, cal)
	Sb <sub>i</sub> <sup>3-</sup>		0.61 (Cd rich, cal)
Bi	total	10 <sup>-10</sup>	0.3-0.4 (exp)

# How do the Solution-based Group V halides Diffuse into the Polycrystalline CdTe?



A potential new p-i-n structure device structure using the ex-situ group V doping: **GB is p-doped, while GI is intrinsic**



1. Initially, diffuse along the grain boundaries and segregate in GBs
2. Then, diffuse from GIs to GBs.
3. However, the diffusion from the GBs to the GIs is limited, which is different to the Cu diffusion.
4. More characterization needed.

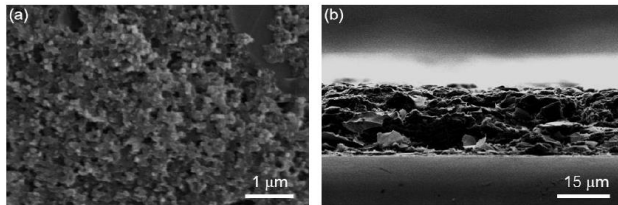


# Challenges to Conduct the ex-situ Group V Doping in CdTe

- Understanding ex-situ Diffusion Doping mechanism
- Higher diffusion barrier of Group V in the CdTe Grain Interiors(GIs)/Grain Boundaries (GBs)
- Complicated surface chemistry of the diffusion doped CdTe surface
- Suitable back contact for the diffusion doped CdTe.
- Alternative group V dopants for ex-situ diffusion
- Desired activation process for the ex-situ diffusion doped CdTe
- Others, e.g., impurities (unintentional dopants)

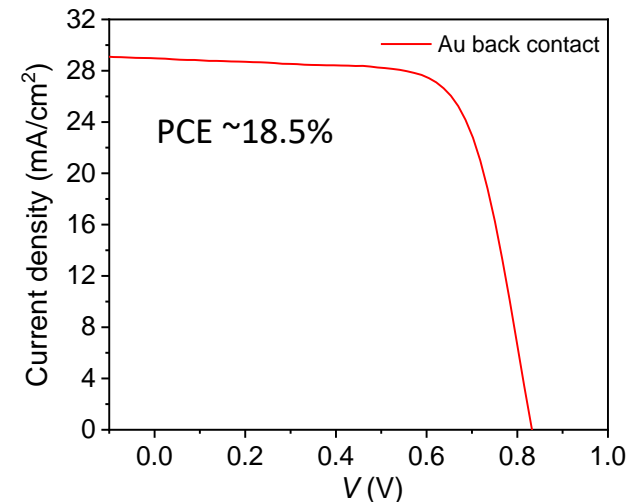
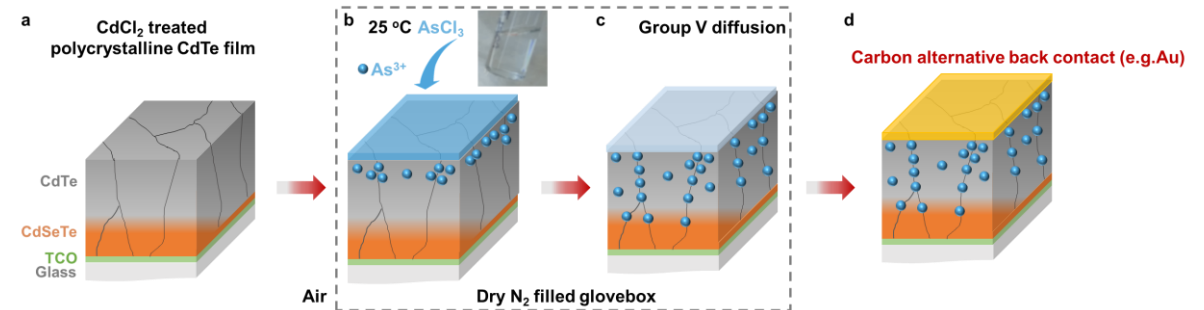
# Alternative Back Contact for the Solution processed Group V Diffusion doped CdTe

- Carbon back contact
  - 18% efficiency
  - Suitable work function
  - Easy to operate in the glovebox



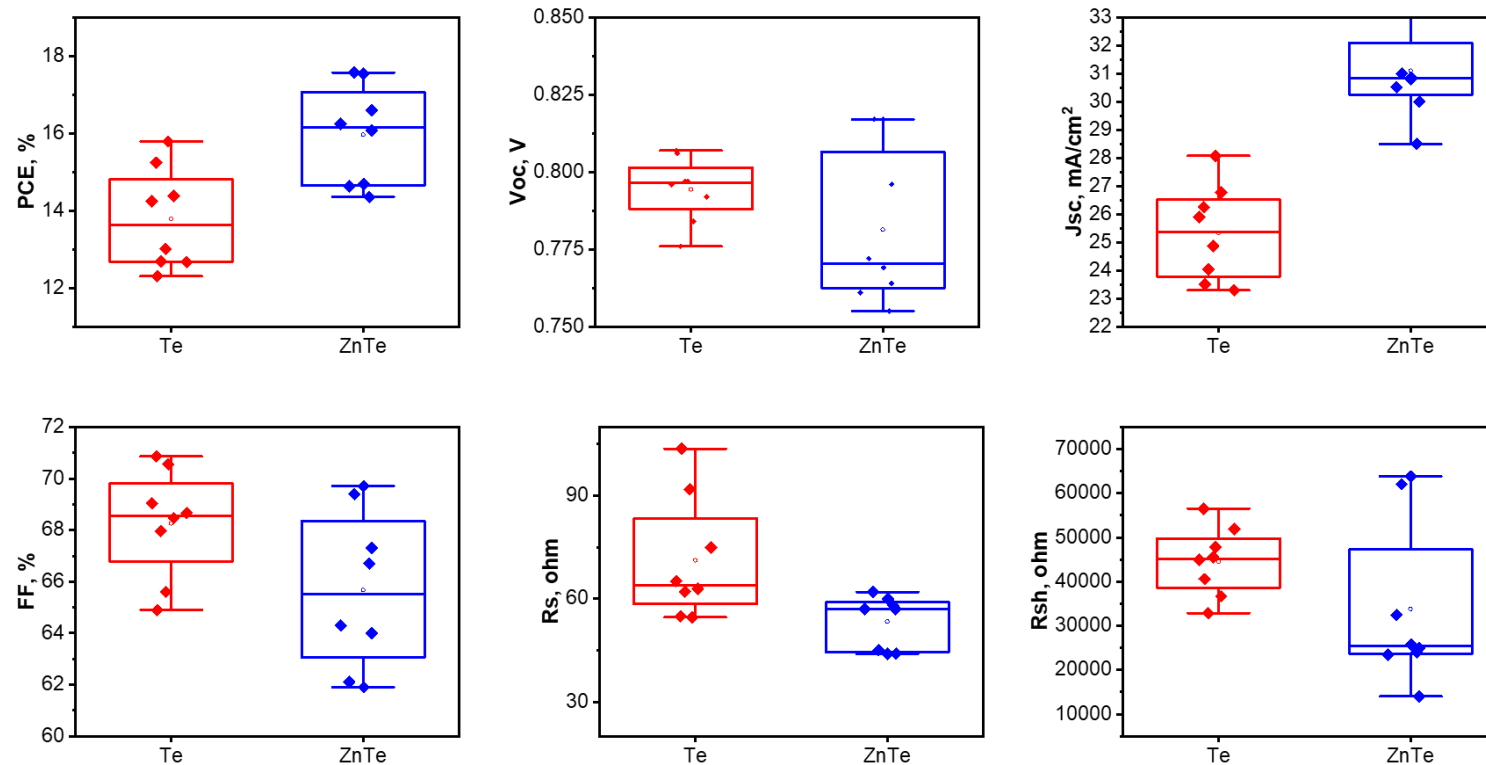
- Concern:
  - High resistivity
  - Porous interface with CdTe
  - Unintentional impurities

- Au back contact
  - Thermal evaporated Au electrode



# Alternative Back Contact for the Solution processed Group V Diffusion doped CdTe

- ZnTe and Te back contact deposited using sputtering



*Other back contact for the heavily doped back surface needed.*

# Opportunities to Conduct the ex-situ Group V Doping in CdTe via solution process

- Ex-situ Diffusion Doping mechanism
- Higher diffusion barrier of Group V in the CdTe Grain Interiors(GIs)/Grain Boundaries (GBs)
- Complicated surface chemistry of the diffusion doped CdTe surface
- Suitable back contact for the diffusion doped CdTe.
- Alternative group V dopants for ex-situ diffusion
- Desired activation process for the ex-situ diffusion doped CdTe
- Others, e.g., impurities (unintentional dopants)

*Hope to get a higher device performance after addressing the above challenges >22%*

# Acknowledgements

## Collaborators:

UT: Dengbing Li, Yanfa Yan, Michael Heben, Randy Ellingson

CSU: Tushar Shimpi, Jim Site, W. S. Sampath,

First Solar: Dingyuan Lu, Xiaoping Liu, Gang Xiong

NREL: Matt Reese

Graduate students: UA: Xiaomeng Duan, Harigovind Gokul

Menon, UT: Sabin Neupane,



CMMI-2019473



DE-EE0009368